



IFW

Docket No.: ISH-0234  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Hideki YAMANAKA et al.

Application No.: 10/543,166

Confirmation No.: 7946

Filed: July 22, 2005

Art Unit: 2812

For: SILICON SEMICONDUCTOR SUBSTRATE AND  
METHOD FOR MANUFACTURING THE SAME

Examiner: Not yet assigned

**STATUS INQUIRY**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

It is respectfully requested that the attorney named below be advised of the status of the above-identified application. Please advise us of when we might expect to receive an Office Action from the Patent and Trademark Office.

Applicant believes no fee is due with this response. However, if a fee is due, please charge our Deposit Account No. 18-0013, under Order No. ISH-0234 from which the undersigned is authorized to draw.

Dated: January 11, 2007

Respectfully submitted,

By   
David T. Nikaido

Registration No.: 22,663

Lee Cheng

Registration No.: 40,949

RADER, FISHMAN & GRAUER PLLC

1233 20th Street, N.W.

Suite 501

Washington, DC 20036

(202) 955-3750

Attorney for Applicant